

#28
1/22/01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

	Sylvia H. Pas	Examiner:	TBD
Serial No:	TBD	Art Unit:	TBD
Filed:	01/11/01	Docket No.:	TI-22398
For:	SYSTEM AND METHOD FOR INTEGRATED OXIDE REMOVAL AND PROCESSING OF A SEMICONDUCTOR WAFER		

PRELIMINARY AMENDMENT

January 11, 2001

Assistant Commissioner for Patents

Washington, DC 20231

Dear Sir:

Please amend the above referenced application as follows:

In the Specification:

Page 1, before line 1, insert --This application claims priority under 35 USC §

119(e)(1) of provisional application numbers 60/178,647 filed 01/28/00.--